

U.S. Department of Commerce, Patent and Trademark	Atty. Docket No.	Application No.
INFORMATION DISCLOSURE STATEMENT BY APPLICANT	TNCR.169US2	10/729,609
	Applicant(s)	C nf. No.
(Use several sheets if necessary)	Thomas McWaid	2888
	Filing Date	Group
	December 5, 2003	2856

U.S. Patent Documents

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
<i>DM</i>	1	2,691,887	Oct., 1954	Rinker.	—	—	
	2	2,728,222	Dec., 1955	Becker et al.	—	—	
	3	3,283,568	Nov., 1966	Reason.	—	—	
	4	4,103,542	Aug., 1978	Wheeler et al.	—	—	
	5	4,391,044	Jul., 1983	Wheeler.	—	—	
	6	4,441,177	Apr., 1984	Groh et al.	—	—	
	7	4,574,625	Mar., 1986	Olasz et al.	—	—	
	8	4,641,773	Feb., 1987	Morino et al.	—	—	
	9	4,669,300	Jun., 1987	Hall et al.	—	—	
	10	4,724,318	Feb., 1988	Binnig.	—	—	
	11	4,883,959	Nov., 1989	Hosoki et al.	—	—	
	12	4,902,892	Feb. 1990	Okayama et al.	250	307	
	13	5,146,690	Sep., 1992	Breitmeier.	—	—	
	14	RE33387	Oct. 1990	Binnig	—	—	
	15	5,162,653	Nov. 1992	Hosaka et al.	250	306	
	16	RE34331	Aug., 1993	Elings et al.	—	—	
	17	5,253,106	Oct., 1993	Hazard.	—	—	
	18	5,266,801	Nov., 1993	Elings et al.	250	306	
	19	5,307,693	May., 1994	Griffith et al.	—	—	
	20	5,308,974	May., 1994	Elings et al.	—	—	
	21	5,309,755	May., 1994	Wheeler.	—	—	
	22	5,347,854	Sep., 1994	Martin et al.	—	—	
	23	5,406,832	Apr., 1995	Gamble et al.	—	—	
	24	5,412,980	May., 1995	Elings et al.	—	—	
	25	5,414,690	May., 1995	Shido et al.	—	—	
<i>DM</i>	26	5,415,027	May 1995	Elings et al.	250	105	

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<i>Dr</i>	27	5,426,302	Jun., 1995	Marchman et al.	—	—	
	28	5,481,521	Jan., 1996	Washizawa et al.	—	—	
	29	5,488,862	Feb., 1996	Neukermans et al.	—	—	
	30	5,497,656	Mar. 1996	Kado et al.	73	105	
	31	5,509,300	Apr., 1996	Chamberlin et al.	—	—	
	32	5,513,168	Apr., 1996	Fujihara et al.	—	—	
	33	5,614,712	Mar. 1997	Ray	73	105	
	34	5,627,365	May., 1997	Chiba et al.	—	—	
	35	5,629,790	May., 1997	Neukermans et al.	—	—	
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	37	5,866,806	Feb. 1999	Samsavar et al.	73	105	
<i>Dr</i>	38	6,028,305	Feb. 2000	Minne et al.	250	306	

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							Translation	
		Document	Date	Country	Class	Subclass	Yes	No
<i>Dr</i>	39	0361932	Sep., 1989	EP.	—	—		
	40	0536827	Sep., 1992	EP.	—	—		
	41	0594362	Oct., 1993	EP.	—	—		
	42	0633450	Jun., 1994	EP.	—	—		
	43	2249910	Oct., 1990	JP	—	—		
	44	2009409	Jun., 1979	GB	73	105		
	45	WO 88/04047	Jun., 1988	WO.	—	—		
	46	WO 94/08204	Apr., 1994	WO	—	—		
	47	WO 94/23888	Nov., 1994	WO.	—	—		
	48	05920	Feb. 1998	WO.	73	105		

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	50	"From Molecules to Cells: Imaging Soft Samples with the Atomic Force Microscope", M. Radmacher et al., Science, vol. 257, Sep. 25, 1992, pp. 1900-1905.
	51	"Dimensional Metrology of Phase-Shifting Masks with Scanning Probe Microscopes," J.E. Griffith et al., SPIE, vol. 2087, Photomask Technology and Management, 1993, pp. 107-118.
	52	"Silicon Wafer Thermal Processing: 300 mm Issues," H. Huff et al., Future Fab International, 1996, pp. 35-49.
	53	"Atomic force microscopy for high speed imaging using cantilevers with an integrated actuator and sensor," S.R. Manalis et al., Appl. Phys. Lett., 68(6), Feb. 5, 1996, pp. 871-873.
	54	"Single-Tube Three-Dimensional Scanner for Scanning Tunneling Microscopy," G. Binnig et al., Review of Scientific Instruments, vol. 57, No. 8, Aug. 1986, pp. 1688-1689.
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	56	"A Stand-Alone Scanning Force and Friction Microscope," M. Hipp et al., Ultramicroscopy, 42-44(1992), Elsevier Science Publishers B.V., pp. 1498-1503.
	57	"New Scanning Device for Scanning Tunneling Microscope Applications," R. Koops et al., Review of Scientific Instruments, vol. 63, No. 8, Aug. 1992, pp. 4008-4009.
	58	"Scanning Tunneling Microscopy," G. Binnig et al., Helvetica Physica Acts, vol. 55, 1982, pp. 726-735.
	59	"Two-Scanning Tunneling Microscope Devices for Large Samples," G.B. Picotto et al., Review of Scientific Instruments, vol. 64, No. 9, Sep. 1993, pp. 2699-2701.
	60	"A High Precision Micropositioner Based on Magnetostriction Principle," W. Wang et al., Review of Scientific Instruments, vol. 63, No. 1, Jan. 1992, pp. 249-254.
	61	"Design and Assessment of Monolithic High Precision Translation Mechanisms," S.T. Smith et al., Journal of Physics E: Scientific Instruments, vol. 20, Aug. 1987, pp. 977-983.

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	63	"Long Range Constant Force Profiling for Measurement of Engineering Surfaces," L.P. Howard, Review of Scientific Instruments, vol. 63, No. 10, Oct. 1992, pp. 4289-4295.
	64	"The National Institute of Standards and Technology Molecular Measuring Machine Project: Metrology and Precision Engineering Design," E.C. Teague, J. Vac. Sci. Technol. B, vol. 7, No. 6, Nov./Dec. 1989, pp. 1898-1902.
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	66	"To Measure a Molecule," F. Flam, pp. 21-24, no date available.
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	70	"Series 88 Fiber-Optic Displacement Sensors," G. J. Philips, Sensors, Feb. 1995.
	71	"Nanometrology," E.C. Teague; Proceedings of Scanned Probe Microscopy; STM and Beyond, an Engineering Foundation Conference, Santa Barbara, CA Jan. 1991.
	72	"Microlever with combined integrated sensor/actuator functions for scanning force microscopy," J. Brugger et al., Sensors and Actuators A, 43, 1994, pp. 339-345.
	73	"Rocking-beam force-balance approach to atomic force microscopy," D.A. Grigg et al., Ultramicroscopy, 42-44, 1992, pp. 1504-1508.
	74	"Scanning force microscope springs optimized for optical-beam deflections and with tips made by controlled fracture," M.G.L. Gustafsson et al., J. Appl. Phys., 76(1), Jul. 1, 1994, pp. 172-181.

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


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	79	"Resonant silicon sensors," G. Stemme, J. Micromech. Microeng., vol. 1, 1991, pp. 113-125.
	80	Written Opinion dated March 29, 2001
	81	International Search Report dated August 30, 2000
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